

ABSTRACT

A tilt sensor capable of measuring a tilt angle by
utilizing piezoresistive effect without selectively etching
5 a substrate having piezoresistors formed therein, wherein the
backside of the silicon substrate 1 having piezoresistors R1
to R4 formed therein is uniformly ground to a deflectable
thickness, both ends of the silicon substrate 1 are supported
by a support member 2, and a weight member 3 is provided at
10 the center of the silicon substrate 1 through a convex portion
3a.